

**AMENDMENT TO THE CLAIMS:**

The following claim set replaces all prior versions, and listings, of claims in the application:

1. (Currently Amended) A substrate having a hydrophobic surface coating comprised of a silicon oxide anchor layer, ~~and a hydrophobic layer~~ and a cross-linking layer which is interposed between the anchor layer and the hydrophobic layer, wherein the hydrophobic layer which covers the cross-link layer and which consists essentially of the humidified simultaneous vapor deposited reaction product of methyltrichlorosilane (MTCS) and dimethyldichlorosilane (DMDCS), and wherein the cross-linking layer consists essentially of the humidified vapor-deposited reaction product of MTCS.

2. (Cancelled)

3. (Currently Amended) The substrate of claim 1 ~~or 2~~, further comprising a capping layer which covers the hydrophobic layer and which consists essentially of the humidified vapor deposited reaction product of trimethylchlorosilane (TMCS).

4. (Currently Amended) The substrate of ~~claim 2~~ claim 1, wherein the humidified vapor-deposited reaction product of MTCS of the cross-linking layer consists essentially of polymethylsilsesquioxane (PMSO), and wherein the humidified simultaneous vapor deposited reaction product of MTCS and DMDCS of the hydrophobic layer is cross-linked polydimethylsiloxane (PMDSO).

5. (Original) The substrate of claim 1, wherein the anchor layer exhibits a haze value of less than about 3.0%.

6. (Original) The substrate of claim 5, wherein the anchor layer exhibits a haze value of less than about 2.0%.

7. (Original) The substrate of claim 6, wherein the anchor layer exhibits a haze value of less than about 1.5%.

8. (Currently Amended) The substrate of ~~claim 2~~ claim 1, wherein the volume ratio of MTCS to DMDCS in the hydrophobic layer is between about 0.15 : 1 to about 1.75 : 1.

9. (Original) The substrate of claim 8, wherein the volume ratio of MTCS to DMDCS in the hydrophobic layer is between about 0.75 : 1 to about 1.25 : 1.

10. (Currently Amended) A process for forming a hydrophobic coating on a glass substrate comprising the steps of:

- (a) forming an anchor layer by contacting a surface of the substrate to be coated with a silicon tetrachloride vapor for a time sufficient to form a silicon oxide layer on the glass surface; ~~and then~~
- (b) forming a hydrophobic layer over the silicon oxide layer by the simultaneous vapor deposition ~~simultaneously contacting the silicon oxide layer with vapors~~ of methyltrichlorosilane (MTCS) and dimethyldichlorosilane (DMDCS) for a time sufficient to form a cross-linked layer of polydimethylsiloxane (PDMSO)<sub>x</sub> and
- (c) interposing a cross-linking layer between the anchor layer and the hydrophobic layer by the humidified vapor deposition of MTCS.

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11. (Original) The process of claim 10, wherein the volume ratio of MTCS to DMDCS is between about 0.15 : 1 to about 1.75 : 1.

12. (Original) The process of claim 11, wherein the volume ratio of MTCS to DMDCS is between about 0.75 : 1 to about 1.25 : 1.

13. (Cancelled)

14. (Currently Amended) The process of claim 10, which further comprising the step of vapor depositing a ~~fluoroalkylsilane~~ chloroalkylsilane capping layer over the hydrophobic layer.

15. (Currently Amended) The process of claim 14, wherein the chloroalkylsilane ~~fluoroalkylsilane~~ capping layer consists essentially of trimethylchlorosilane (TMCS).

16. (Currently Amended) A coated glass substrate made by the process of ~~any one of claims 10-15~~ claim 10, 11, 12, 14 or 15.